

A Fast Prototyping Process for Fabrication of Microfluidic Systems on Soda-Lime Glass

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Objectives

- ❑ Use soda-lime glass as the substrate materials.
- ❑ Develop the wet etching mask using AZ4620 photoresist.
- ❑ Develop a new etching process for soda-lime glass in HF based etchant.
- ❑ Develop a rapid and reliable fusion bonding process for soda-lime glass.

Materials

□ Glass substrates:

- polished soda-lime glass (w/o annealing)

(G-Tech optoelectronics Crop, Taiwan)

- microscope glass slides (anneal at 400 °C for 4 hr)

(Marienfeld, Germany)

Both of the glass substrates were cleaned in boiling Piranha solution for 10 min.

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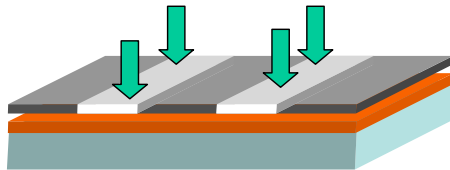
Fabrication processes



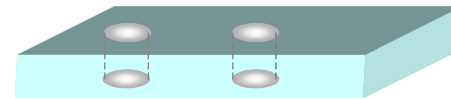
PR spin-coating and soft baking



PR stripping



UV Exposure

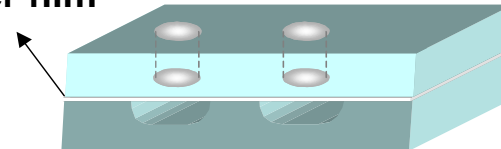


Cover glass drilling



Photoresist developing and hard baking

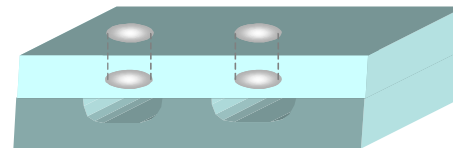
DI water film



Cleaning and alignment

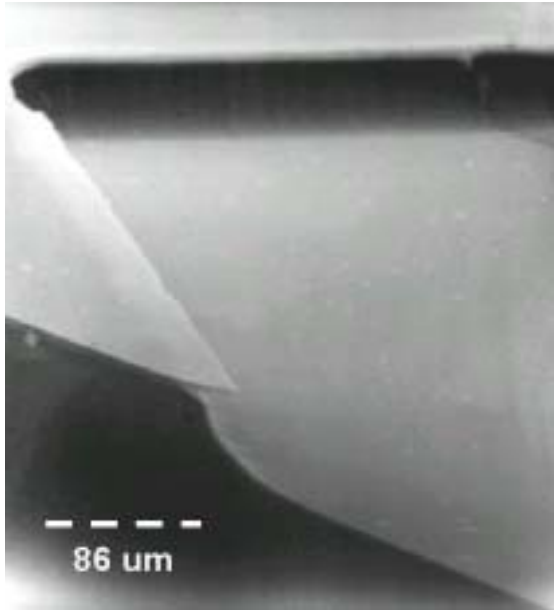


BOE etching in ultrasonic bath

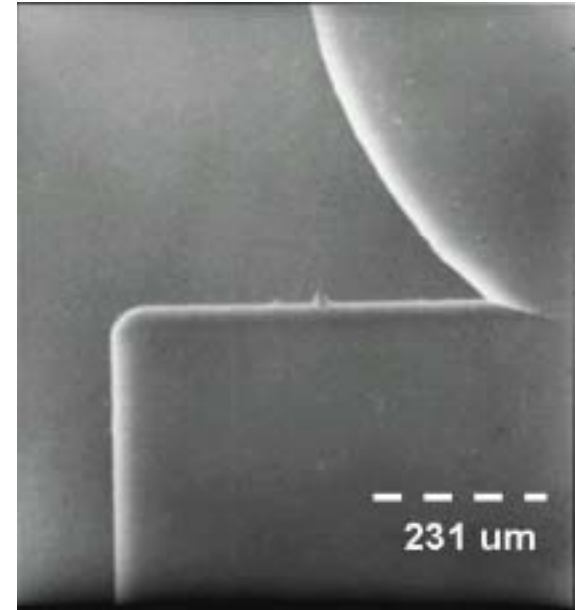
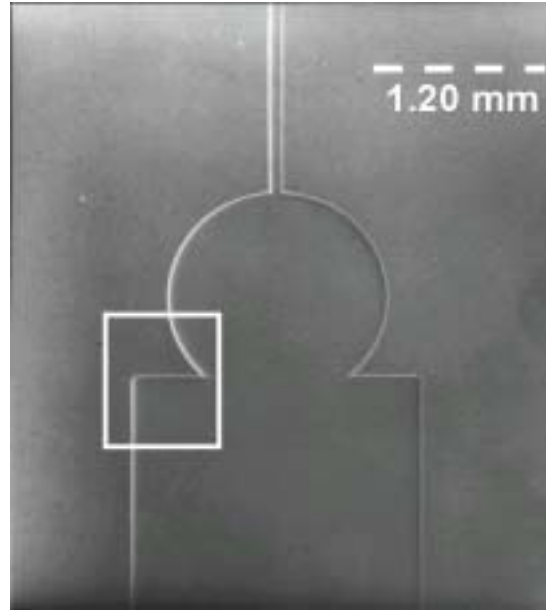


Fusion bonding

SEM view of etched substrates



AZ4620 etching mask PR stripped

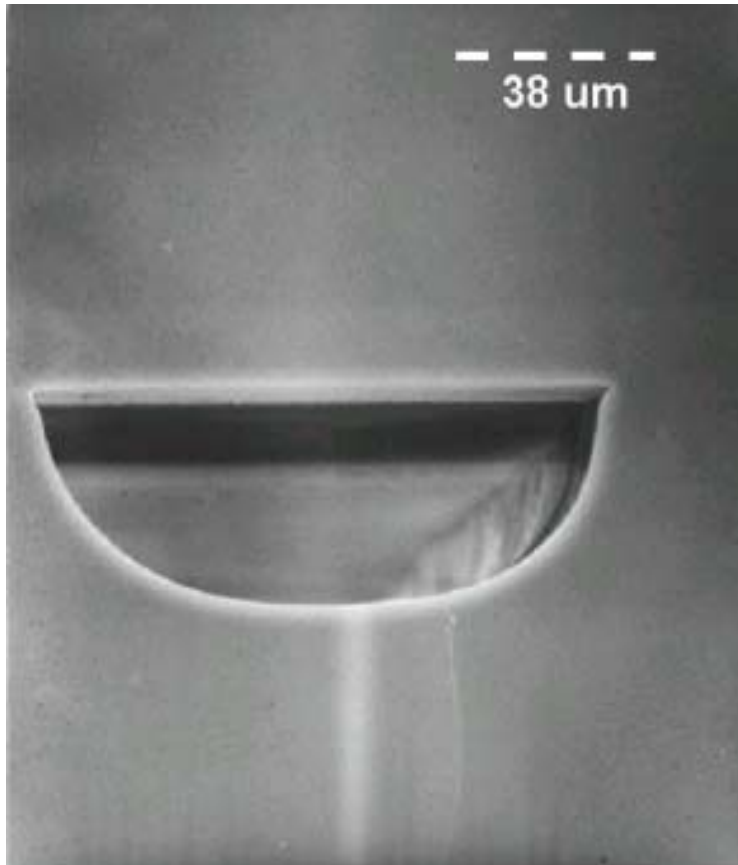


Close-up view of a convex corner

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Channel cross section after fusion bonding



- ❑ No Interface observed after fusion.
- ❑ No distortion occurred after fusion bonding
- ❑ Ultrasonic agitation resulted in an isotropic etching channel.

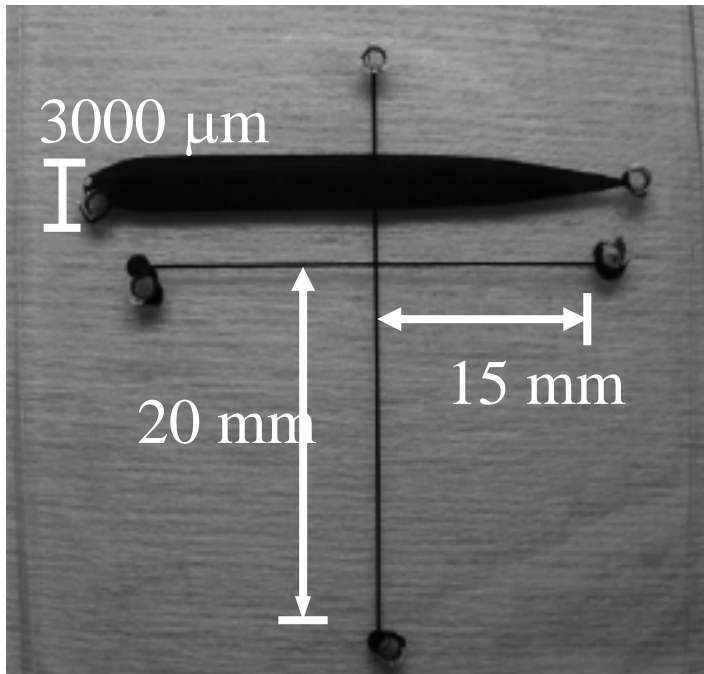
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etching mask dimension: 20 μm

channel dimension: 36 μm deep, 92 μm wide

Microfluidic devices fabricated by the developed process



Flow-through sampling microchip

No collapse occurs at the 3 mm wide channel.



Flow cytometer

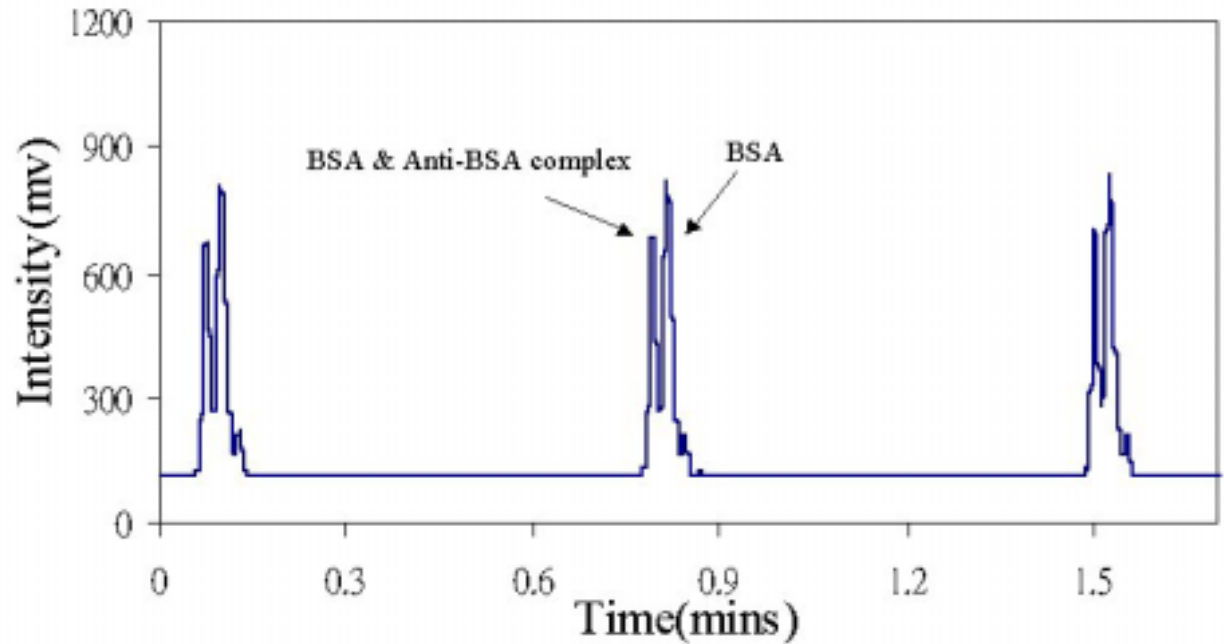
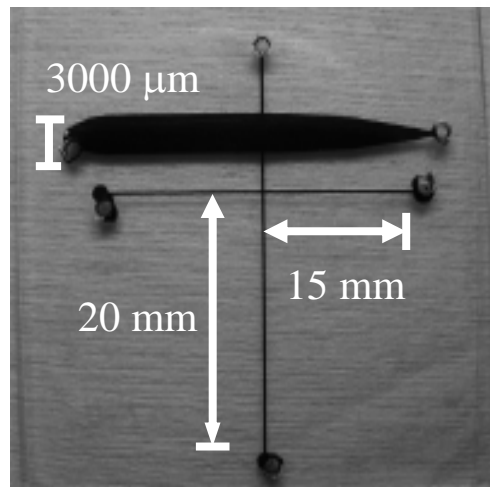


Micro CE chip

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Bioanalysis of a flow-through sampling microchip



Samples: Cy-5 labeled BSA (5 ppm) and anti-BSA (3.8 ppm)

Buffers: 20 mM Na_2HPO_4 , pH=7.4

Flow rate: 2 $\mu\text{L}/\text{min}$

Separation voltage: 1.3 kV

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Summaries

- ❑ A low-cost process was developed to fabricate microfluidic devices using soda-lime glass.
- ❑ A novel etching process was developed to remove the forming participates.
- ❑ A fast but reliable bonding process was developed to seal the channels without sophisticate heating and cooling procedures.
- ❑ The whole process can be done within 10 hours.